

**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

In re Application for:

**Kevin J. Lee**

Serial No. 10/808,763

Filed: March 24, 2004

For: CONTROLLED POTENTIAL ANODIC ETCHING  
PROCESS FOR THE SELECTIVE REMOVAL OF  
CONDUCTIVE THIN FILMS

Examiner: Lois L. Zheng

Art Unit: 1742

**SUBMISSION PURSUANT TO 37 C.F.R. § 1.114**

Mail Stop RCE  
Commissioner for Patents  
P.O. Box 1450  
Alexandria, Virginia 22313-1450

Dear Ma'am:

Pursuant to 37 CFR § 1.114, Applicants submit the following amendment and remarks in addition to the fee set forth in 37 CFR § 1.17(e).

**Amendments to the Claims** are reflected in the listing of claims and begins on page 2 of this response.

**Remarks/Arguments** begin on page 3 of this response.